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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLN. OF: ASPAR et al.
SERIAL NO: 09/777,516
FILED: February 6, 2001
FOR: METHOD OF PRODUCING A THIN LAYER OF ...
GROUP: 2823
EXAMINER: FOURSON III, George DOCKET: BREV 12370 CON3

MAIL STOP ISSUE FEE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


TRANSMITTAL LETTER

Dear Sir:

The Notice of Allowability mailed May 25, 2004 does not acknowledge two IDS's filed by the Applicants on May 10 and May 12, 2004. Enclosed are additional copies of the IDS's. Since the IDS's were previously filed, it is respectfully submitted that no copies of these references are believed necessary. Also, no fee is believed necessary since the IDS's were filed before issuance of the Notice of Allowance.

Please initial and enter the previously filed IDS's and return copies to the undersigned.

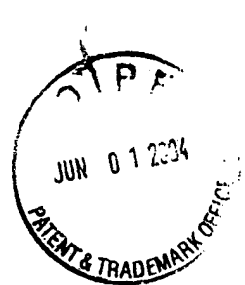
Respectfully requested,


Norman P. Soloway
Attorney for Applicant
Reg. No. 24,315

HAYES SOLOWAY P.C.
130 W. CUSHING ST.
TUCSON, AZ 85701
TEL. 520.882.7623
FAX. 520.882.7643

175 CANAL STREET
MANCHESTER, NH 03101
TEL. 603.668.1400
FAX. 603.668.8567





Serial No. 09/777,516
Docket Number BREV 12370 CON3
TRANSMITTAL LETTER

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: MAIL STOP ISSUE FEE, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

May 27, 2004 at Tucson, Arizona

By: Kim Good

NPS:kg

HAYES SOLOWAY P.C.

130 W. CUSHING ST.
TUCSON, AZ 85701
TEL. 520.882.7623
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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Dear Sir:

In connection with the above-entitled matter, Applicants hereby proffer U.S. Patent Office Form PTO-1449, including copies of the references listed therein. These references came to applicants' attention in connection with litigation concerning a related U.S. Patent. The claims in the present application are believed to be patentably distinguished over these references.

This Supplemental Information Disclosure Statement is being made pursuant to the duty of disclosure imposed by law and formulated in 37 CFR 1.56(A). No representation is made that the information thus disclosed in fact constitutes prior art or that it is the closest prior art, inasmuch as 37 CFR 1.56(A) relies on a materiality concept which depends on subjectivity.

This Supplemental Information Disclosure Statement is being filed prior to the issuance of a further action following the filing of the Request for Continuation of Examination.




HAYES SOLOWAY P.C.
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TUCSON, AZ 85701
TEL. 520.882.7623
FAX. 520.882.7643

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MANCHESTER, NH 03101
TEL. 603.668.1400
FAX. 603.668.8567

Therefore, we believe there are no fees involved with this Information Disclosure Statement. In the event there are additional fees payable, please charge them to our Deposit Account No. 08-1391.

Respectfully submitted,


Norman P. Soloway
Attorney for Applicants
Reg. No. 24,315

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on May 10, 2004 at Tucson, Arizona.

By: 

HAYES SOLOWAY P.C.
130 W. CUSHING ST.
TUCSON, AZ 85701
TEL. 520.882.7623
FAX. 520.882.7643

175 CANAL STREET
MANCHESTER, NH 03101
TEL. 603.668.1400
FAX. 603.668.8567

INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

JUN 01 2004

Docket Number (Optional)

BREV 12370 (3

Application Number

09/777,516

Applicant(s)

ASPAR et al.

Filing Date

February 6, 2001

Group Art Unit

2823

*EXAMINER
INITIAL

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

"Hydrogen-Related Complexes as the Stressing Species in High-Fluence, Hydrogen-Implanted, Single-Crystal Silicon" Cerofolini et al., *Physical Review B*, Volume 46, Number 4, 1992, pgs. 2061-2070

"Crystallographic Nature and Formation Mechanisms of Highly Irregular Structure in Implanted and Annealed Si Layers" Komarov et al., *Radiation Effects*, Volume 42, 1979, pgs. 169-178

"Observation of Blistering and Amorphization on Germanium Surface After 450 keV Ar+ION Bombardment" Kamada et al., *Radiation Effects*, Volume 28, 1976, pgs. 43-48

"Orientation Dependence of Flaking of Ion Irradiated Aluminum Single Crystals" Ono et al., *Japanese Journal of Applied Physics*, Volume 25, No., 10, 1986, pgs. 1475-1480

"High Fluence Retention of Noble Gases Implanted in Silicon" Wittmaack et al., *Radiation Effects*, Volume 39, 1978, pgs. 81-95

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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By:

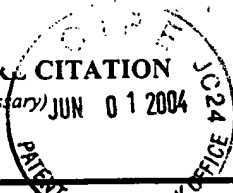
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"Applications of Ion Beams to Materials, 1975" Carter et al., Inst. Phys. Conf. Ser. No. 28, Chapter 1, 1976, pgs. 30-36

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